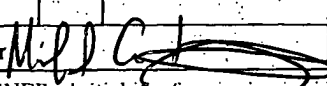


U.S. Department of Commerce, Patent and Trademark Office  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use several sheets if necessary)					Application No.:		Unknown	
					Filing Date:		Unknown	
					First Named Inventor:		Jaime Poris	
					Group Art Unit:		Unknown	
					Examiner Name:		Unknown	
					Confirmation No.:		Unknown	
Copies of References located in Parent Application Serial No. 09/724,813					Attorney Docket No.:		NAN042-1D US	
U.S. Patent Documents								
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
ML	1.	5,314,843	5/24/1994	Yu et al	437	225		
ML	2.	5,348,002	9/20/1994	Caro	128	633		
ML	3.	5,555,471	10-Sep-96	Xu et al.	356	357		
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							Translation	
		Document	Date	Country	Class	Subclass	Yes	No.
ML	14.	EL 0 831 295 A1	3/25/1998	EP				
ML	15.	EP 0 982 774 A2	3/1/2000	EP				
ML	16.	WO 00/54325	9/14/2000	PCT				
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
ML	17.	Azzam, R. "Ellipsometry and Polarized Light" Elsevier Science B.V. (1977, 1987); Pages 282-287						
Examiner <i>ML</i>		Date Considered <i>February 17, 2004</i>						
*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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		Examiner Name:	Unknown
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ML	18.	Fujiwara, H et al., "Dept-profiles in compositionally-graded amorphous silicon alloy thin films analyzed by real time spectroscopic ellipsometry" <i>Elsevier Science S.A.</i> pages 474-478.(1998)	
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Examiner			
	Date Considered	February 17, 2004	
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